## **PROCEEDINGS OF SPIE**

# Two- and Three-Dimensional Methods for Inspection and Metrology VI

Peisen S. Huang Toru Yoshizawa Kevin G. Harding Editors

10–11 August 2008 San Diego, California, USA

Sponsored and Published by SPIE

Volume 7066

Proceedings of SPIE, 0277-786X, v. 7066

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Author(s), "Title of Paper," in Two- and Three-Dimensional Methods for Inspection and Metrology VI, edited by Peisen S. Huang, Toru Yoshizawa, Kevin G. Harding, Proceedings of SPIE Vol. 7066 (SPIE, Bellingham, WA, 2008) Article CID Number.

ISSN 0277-786X ISBN 9780819472861

Published by **SPIE** P.O. Box 10, Bellingham, Washington 98227-0010 USA Telephone +1 360 676 3290 (Pacific Time) · Fax +1 360 647 1445 SPIE.org

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Printed in the United States of America.

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